

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Applicant(s): George D. Papasouliotis; Robert D. Tas; Patrick A. Van Cleemput; Bart van Schravendijk
Assignee: Novellus Systems, Inc.
Title: PROCESS FOR DEPOSITING F-DOPED SILICA GLASS IN HIGH ASPECT RATIO STRUCTURES
Serial No.: 10/035,773 Filed: December 21, 2001
Examiner: Unassigned Group Art Unit: 1745
Docket No.: M-5091-2P US

Newport Beach, California
March 4, 2002

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Sir:

Please direct all correspondence in the above-identified application and with respect to any patent that issues on this application to the undersigned at this address:

Tom Chen
c/o SKJERVEN MORRILL MacPHERSON LLP
25 Metro Drive, Suite 700
San Jose, California 95110
Telephone: (949) 718-5200

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Sandy Kim

3/4/02

Date of Signature

Respectfully submitted,

Tom Chen
Attorney for Applicant(s)
Reg. No. 42,406

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LAW OFFICES OF
SKJERVEN MORRILL
MACPHERSON LLP

25 METRO DRIVE
SUITE 700
SAN JOSE, CA 95110
(408) 453-9200
FAX (408) 453-7979

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